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Examiner Initials*	Cite No.	U.S. Patent or Application Kind Code NUMBER (if known)	Name of Patentee or Inventor of Cited Document	Date of Publication or Filing Date of Cited Document	Pages, Columns, Lines, Where Relevant Passages or RelevantFigures Appear	
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<u></u>	AD	(Atty. Docket No. MTI-31044) U.S. Application No. 09/887,767	Lee et al.	Filed 06/21/2001	TECHNOLOGI GENTA	
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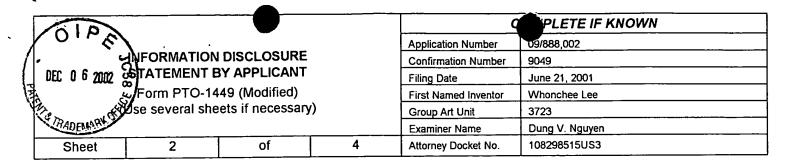
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Form PTO-1449 (Modified) (Use several sheets if necessary)				Confirmation Number	9049	
				Filing Date	June 21, 2001	
	Form PTO-14	449 (Modified)	First Named Inventor	Whonchee Lee		
(Use several sheets if necessary)				Group Art Unit	3723	
OF HEALTH			Examiner Name	Dung V. Nguyen		
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